

Abstract

An object of this invention is to provide a vacuum apparatus used in the field of semiconductor production and capable of suppressing power consumption.

The vacuum apparatus comprises vacuum containers (10, 11, 12, 13, 14, and 15) having gas inlets and gas outlets, vacuum pumps of at least one stage for depressurizing the inside of the vacuum containers or maintaining the inside of the container in a depressurized state, and compressors (4c, 5c, 6c, 7c, 8c, and 9c) connected to the discharge ports of the vacuum pumps (4b, 5b, 6b, 7b, 8b, and 9b) on the last stage among the vacuum pumps and having capacities having capability of depressurizing the input sides thereof.